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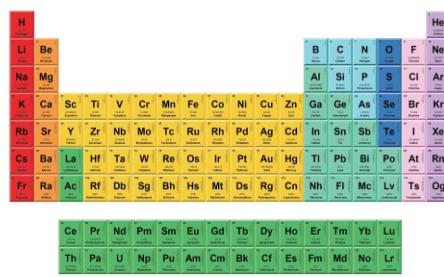
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Comprehensive characterization of nitrogen-related defect states in β -Ga₂O₃ using quantitative optical and thermal defect spectroscopy methods

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ABSTRACT

This study provides a comprehensive analysis of the dominant deep acceptor level in nitrogen-doped beta-phase gallium oxide (β -Ga₂O₃), elucidating and reconciling the hole emission features observed in deep-level optical spectroscopy (DLOS). The unique behavior of this defect, coupled with its small optical cross section, complicates trap concentration analysis using DLOS, which is essential for defect characterization in β -Ga₂O₃. A complex feature arises in DLOS results due to simultaneous electron emission to the conduction band and hole emission to the valence band from the same defect state, indicating the formation of two distinct atomic configurations and suggesting metastable defect characteristics. This study discusses the implications of this behavior on DLOS analysis and employs advanced spectroscopy techniques such as double-beam DLOS and optical isothermal measurements to address these complications. The double-beam DLOS method reveals a distinct hole emission process at $E_V + 1.3$ eV previously obscured in conventional DLOS. Optical isothermal measurements further characterize this energy level, appearing only in N-doped β -Ga₂O₃. This enables an estimate of the β -Ga₂O₃ hole effective mass by analyzing temperature-dependent carrier emission rates. This work highlights the impact of partial trap-filling behavior on DLOS analysis and identifies the presence of hole trapping and emission in β -Ga₂O₃. Although N-doping is ideal for creating semi-insulating material through the efficient compensation of free electrons, this study also reveals a significant hole emission and migration process within the weak electric fields of the Schottky diode depletion region.

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Extrinsic dopant incorporation in semiconductors controls the Fermi-level position in the bandgap, resulting in conductive or semi-insulating epilayers/substrates.^{1–3} In beta-phase gallium oxide (β -Ga₂O₃), which possesses inherent n-type conductivity, impurities such as Si, Ge, and Sn are common donors that efficiently create free electrons and n-type conductivity due to the shallow nature of their energy levels in the bandgap.^{1–4} In contrast, impurities such as nitrogen,⁵ iron,⁶ magnesium,¹ cobalt,⁷ and nickel⁸ are theoretically and experimentally verified to introduce acceptor-like bandgap states in β -Ga₂O₃ that are very deep in the bandgap at $E_C - 2.9$ eV, $E_C - 0.8$ eV, $E_C - 3.8$ eV, $E_C - 1.9$ eV, and $E_C - 2.2$ eV, respectively. These deep

acceptor states can compensate for excess electrons and pin the Fermi level at the deep acceptor energy level, thus creating highly resistive or semi-insulating layers necessary for high breakdown and radio frequency (RF) β -Ga₂O₃ devices. Our prior work investigated energy levels associated with N doping by deep-level optical spectroscopy (DLOS) since it is an intriguing and promising deep acceptor candidate.⁵ Nitrogen doping in β -Ga₂O₃ is highly stable due to its 3.87 eV barrier diffusion activation energy^{1,9} and its primary acceptor energy at $\sim E_C - 2.9$ eV as predicted by theoretical calculations for the oxygen site III (N_{OIII}), which DLOS corroborated.⁵ However, a complicating factor created for DLOS characterization

when states are below half of the bandgap ($E_g/2$) for n-type material is that incoming photons can cause electron photoemission to the conduction band and competing hole emission (electron capture from) to the valence band.¹⁰ If not accounted for, this competition makes determining the accurate concentration of such defect states via DLOS difficult, and it can even change the sign of the measured steady-state photocapacitance (SSPC) depending on which process is dominant. In conventional semiconductors such as GaN, negative excursions in the SSPC due to states below midgap can be easily attributed to hole emission to the valence band and subsequent hole collection.^{10,11} However, for β -Ga₂O₃, free holes are relatively immobile and are immediately captured through self-trapping (which leads to its lack of p-type conductivity).^{12–14} Our prior published work on the E_c -2.9 eV (N_{OIII}) acceptor state circumvented this issue by using a +0.7 V forward bias filling pulse during the trap filling stage of the DLOS measurement to ensure complete saturation of this state by electrons through the current injection.⁵ Conventional DLOS measurements using a 0 V filling bias pulse revealed behavior suggesting that both conduction band and valence band emission/capture processes from the same E_c -2.9 eV state are present despite the lack of p-type conductivity. Thus, the purpose of this work is to explore and resolve this possible dual-band behavior in significant detail using a method known as double-

beam DLOS.^{10,15,16} Various pump–probe combinations of light source energies are used to isolate and then quantify both electron and hole emission processes related to the N_{OIII} defect. This study aims to offer new fundamental experimental data on conduction and valence band processes originating from deep states in β -Ga₂O₃. This analysis is crucial for accurately interpreting DLOS data and understanding the photophysics related to these processes in β -Ga₂O₃.

The dual beam DLOS studies were conducted on the samples we characterized in our prior work.⁵ Briefly, halide vapor phased epitaxial (HVPE) grown β -Ga₂O₃ samples¹⁷ with a background Si doping of $1.2 \times 10^{17} \text{ cm}^{-3}$ were implanted with N to create a uniform N concentration of $2 \times 10^{16} \text{ cm}^{-3}$ for a thickness of 1 μm .^{5,9} The N-implanted sample was annealed at 1100 °C for 10 mins in N₂ ambient for N acceptor activation. Subsequently, 8 nm thick semi-transparent Ni-Schottky diodes were fabricated using a two-step lithography process, and an ohmic stack of Ti/Al/Ni/Au was deposited on the back side of the conductive substrate.^{5,18–21} The extracted doping concentration from capacitance–voltage (CV) characteristics was $\sim 1.2 \times 10^{17} \text{ cm}^{-3}$, consistent with the background Si. With the addition of N co-doping, the CV net doping reduced to a value of $0.9\text{--}1 \times 10^{17} \text{ cm}^{-3}$, moving the calculated Fermi level to ~ 0.1 eV below the conduction band. While the DLOS

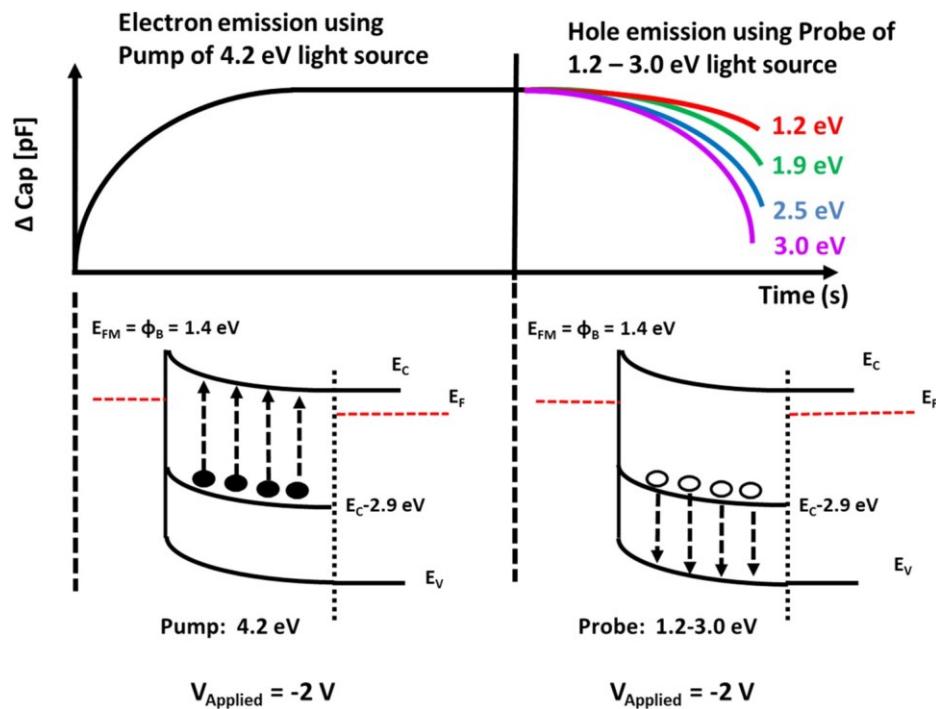


FIG. 1. Schematic of a double beam DLOS experiment showing the light source (pump = 4.2 eV) emitting the nitrogen-related level with a corresponding increase in ΔC and the second monochromatized light source (probe = 1.2–3.0 eV) for the hole emission process/trap refilling causing a decrease in ΔC . The corresponding band diagram illustrates the emission process from the defect state at the pump and probe processes.

technique has been explained previously, the double-beam DLOS method is less known and is described herein. Conducted at a constant temperature of 305 K, the first step is to fill all defect states using a forward bias

pulse of 1.5 V for 600 s. This causes a 2 mA current to flow through the Schottky diode, saturating the traps with electrons. As discussed earlier, a higher current value for the experiment is selected to ensure all defect levels are completely filled with electrons via current injection. After applying the fill pulse, an immediate reverse bias of -2 V was applied while illuminating light through the semi-transparent Ni Schottky metal using a 9 W 4.2 eV UV-LED light source (pump). The light source emits electrons to the conduction band from all states whose energy levels are less than 4.2 eV below the conduction band edge, including the N state at E_c -2.9 eV. The higher energy light source was selected such that the entire spectrum of the optical cross section^{22,23} for this N state is excited,⁵ yet at an energy level low enough so that it does not result in electron emission from the commonly reported E_c -4.4 eV defect state based on the detailed optical cross section analysis of this state from our prior work.²⁰ The pump source was deactivated upon complete emission of the E_c -2.9 eV state, confirmed by observing saturation of the emission transient, followed by subsequent illumination using the probe light. The optical probe source was facilitated using a 450 W Xe-Arc lamp light dispersed through a monochromator to vary the probe photon energy from 1.2 to 3.0 eV in increments of 0.05 eV. During the probe process, the diode was maintained at a constant reverse bias of -2 V and was repeated for each probe energy step. The subsequent photocapacitance transient for each probe energy was digitally recorded. A schematic of the dual beam DLOS experiment is shown in Fig. 1, along with the corresponding band diagrams to help visualize the assumed electron and hole emission processes that the subsequently described experimental results will verify. The sign of the transient allows the differentiation between electron emission to the conduction band (i.e., a positive transient due to an increase in positive space charge) and hole emission to the valence band (i.e., a negative transient due to an increase in negative space charge). In the double beam DLOS measurements, the electron emission dominates during the pump process, followed by hole emission to the valence band during the probe process. The entire process is schematically depicted in Fig. 1.

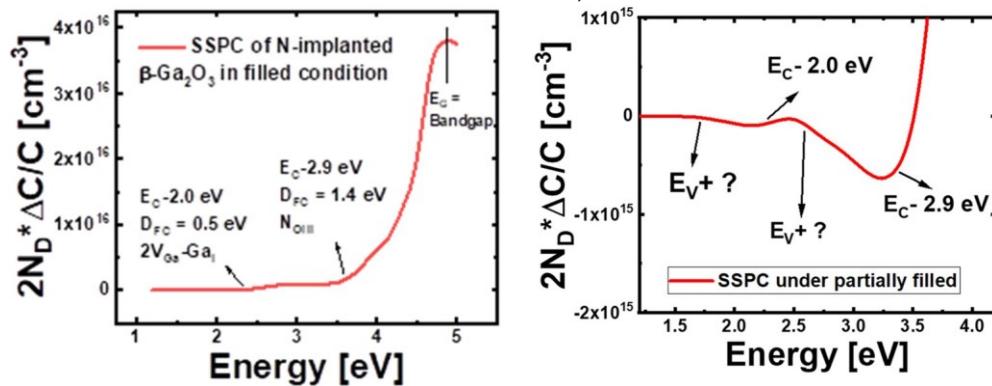


FIG. 2. SSPC results using (a) the 0.7 V filling pulse voltage reported by Ghadi *et al.*⁵ and (b) the standard 0 V filling pulse voltage. The two positive onsets indicated are due to electron photoemission to E_c from defect energy levels at E_c -2.0 eV and E_c -2.9 eV determined from optical

The difference in the sign of the photocapacitance transients will manifest in the SSPC spectrum. Before describing the doublebeam DLOS results, it is helpful to show this effect on the SSPC response, especially as it motivates why both conduction and valence band processes must be investigated. Figures 2(a) and 2(b) compare the SSPC spectra measured using conventional methods with a 0.7 and 0 V fill pulse bias, respectively, followed by the spectrally resolved photoemission experiment at a -2 V reverse bias. With forward bias fill pulse, we are forcing all defect levels to fill through the current injection, and the DLOS results have been published in Ghadi *et al.*⁵ Both positive and negative photocapacitance onsets are observed in Fig. 2(b), indicating interaction with the conduction and valence band, respectively, when using a 0 V fill pulse bias. The positive onsets are due to electron photoemission (increase in positive space charge) to the conduction band, and the negative onsets are due to hole emission (increase in negative space charge) to the valence band. The positive onsets seen at 2.3 and 3.4 eV photon energies in both Figs. 2(a) and 2(b) are from the E_c -2.0 eV and E_c -2.9 eV defect levels emission previously reported.⁵ The former has been found to possess a Franck-Condon energy (D_{FC}) of 0.5 eV²⁰ and has been associated with the predicted $2V_{Ga_2Ga_1}$ defect level.^{19,20,24-26} The latter positive SSPC onset at E_c -3.4 eV has also been studied and is due to the N_{OII} state at E_c -2.9 eV with a D_{FC} = 1.4 eV.^{1,5} However, the SSPC spectrum measured with a 0 V fill pulse reveals the presence of negative onsets, a large one that initiates near photon energy of 2.5 eV and a smaller one near 1.5 eV, which are of primary focus here. As described above, such photocapacitance behavior can only be associated with an increase in negative space charge, and so this warrants deeper investigation with the aforementioned dual beam DLOS.

Figure 3(a) shows room temperature (305 K) double-beam DLOS experimental results. The negative slope of the recorded photocapacitance transients during the probe measurement is consistent with increasing negative space charge due to hole emission. The large timescale on the x-axis indicates that these are very slow transients, and this is consistent with a high hole effective mass,

cross section analysis as reported in Ghadi *et al.*,⁵ while the two negative onsets denoted by $E_V+?$ in (b) in the measured SSPC imply hole emission processes to E_V .

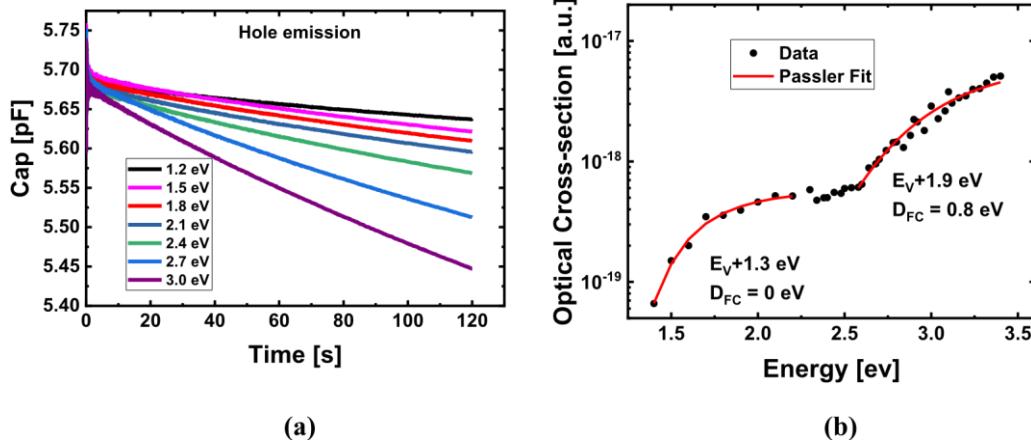


FIG. 3. (a) Measured negative capacitance transient from the hole emission process using the double beam DLOS measurements (probe). (b) Extracted optical cross section from the negative transients exhibiting two distinct onsets when fitted to the Passler model²² results in two defect states at $E_V+1.3 \text{ eV}$ ($D_{FC} = 0 \text{ eV}$) and $E_V+1.9 \text{ eV}$

($D_{FC} = 0.8 \text{ eV}$), respectively.

noting that it is only because of the drift field in the Schottky barrier depletion region that any hole collection is possible. Such observations of hole transport due to a drift field have been previously reported for β -Ga₂O₃ photodetectors.^{27,28} A simple analytical model was developed to substantiate this further as part of this work. The model utilizes the electric field calculated by solving the Poisson equation to extract the hole drift velocity, assuming the reported hole mobility value of $10^{-6} \text{ cm}^2/\text{V}\cdot\text{s}$.²⁹ The travel time is calculated by integrating the velocity over the depletion region. This model reveals that $\sim 50 \text{ ms}$ would be required to allow a photogenerated hole to drift across the depletion region and be collected for a drift field of 0.01 MV/cm . In our double-beam experiments, we applied a minimum electric field of 0.08 MV/cm across the depletion region. In addition, we measured transients over 100 s to ensure the collection of photoemitted holes.

From the photocapacitance transients, the optical cross sections associated with the hole emission transients could be extracted, as shown in Fig. 3(b). Two distinct states are immediately evident, one with a relatively sharp onset starting around 1.3 eV and saturating near 2 eV and one with a broader onset that starts around 2.6 eV . A sharp onset indicates a low D_{FC} energy, implying negligible local lattice relaxation associated with that defect, thus leading to similar emission energies for optical and thermal transitions. In contrast, a broad onset usually indicates a substantial D_{FC} linked to local lattice relaxation.^{22,23} Consequently, the optical transition occurs at the sum of thermal transition energy and high D_{FC} .³⁰ Therefore, the optical cross section should be modeled using either the Passler model²² or the Chantre Vincent and Bois (CVB)²³ model

to extract energy levels, as they incorporate Frank–Condon energies accurately.

The optical cross sections for these two hole emission states were fitted to the Passler model to extract the precise trap and Franck–Condon (D_{FC}) energies.²² The extracted energies correlate with the negative going excursions in the SSPC discussed earlier in Fig. 2(b). The two different energy levels are derived from fitting and are located at $E_V+1.3 \text{ eV}$ ($D_{FC} = 0 \text{ eV}$) and $E_V+1.9 \text{ eV}$ ($D_{FC} = 0.8 \text{ eV}$). The $E_V+1.9 \text{ eV}$ position in the bandgap lines up remarkably close to the $E_c-2.9 \text{ eV}$ state revealed by electron photoemission to the conduction band (i.e., $1.9 \text{ eV} + 2.9 \text{ eV} = 4.8 \text{ eV}$ bandgap) that has been attributed to N_{O_{III}}, and perhaps this is the same defect level.⁵ The level at $E_V+1.3 \text{ eV}$, which is also implied by the slight negative slope of the SSPC data in that energy range from Fig. 2(b), needs further investigation. Interestingly, its modeled D_{FC} is 0 eV , suggesting insignificant lattice relaxation. Similar to the $E_c-2.9 \text{ eV}/E_V+1.9 \text{ eV}$ level, we have only seen evidence for the $E_V+1.3 \text{ eV}$ state for β -Ga₂O₃ doped with N (including not being observed in samples subjected to damage via high energy particle irradiation),^{5,19,31} suggesting a possible association with an N-related defect.

We can now focus on defect concentrations of these levels based on their communication with the valence band. Figure 4 shows the comprehensive pump–probe process, allowing the direct and independent interrogation of electron and hole emission using double-beam DLOS coupled with a laser source. Figure 4(a) shows the 4.2 eV pump process that emits all trapped electrons from any state within 4.2 eV from the conduction band after the electrical electron filling pulse, including both $E_c-2.9$ ($E_V+1.9 \text{ eV}$) and $E_V+1.3 \text{ eV}$ states. Subsequently, Fig. 4(b) shows the probe results that can isolate and quantify the hole emission processes via two laser sources. The laser sources are selected such that a higher photon

flux, i.e., several orders higher than a xenon arc lamp, expedites the emission process. Based on the optical cross section results from Fig. 4(b), only holes from the $E_v+1.3$ eV state will be completely emitted using a red laser probe source (1.8 eV), while both the $E_v+1.3$ eV and $E_v+1.9$ eV states will emit holes using a purple laser probe (3.1 eV) source. The measured trap concentrations of $E_v+1.3$ eV and $E_v+1.9$ eV states based solely on saturating the hole emission were 3.1×10^{15} and $1.74 \times 10^{16} \text{ cm}^{-3}$, respectively. Considering the $E_v+1.9$ eV state, this concentration is very close to the trap concentration obtained solely based on electron emission to the conduction band at $E_c-2.9$ eV, with both matching the N concentration from SIMS, providing strong evidence that, indeed, this is the same N state

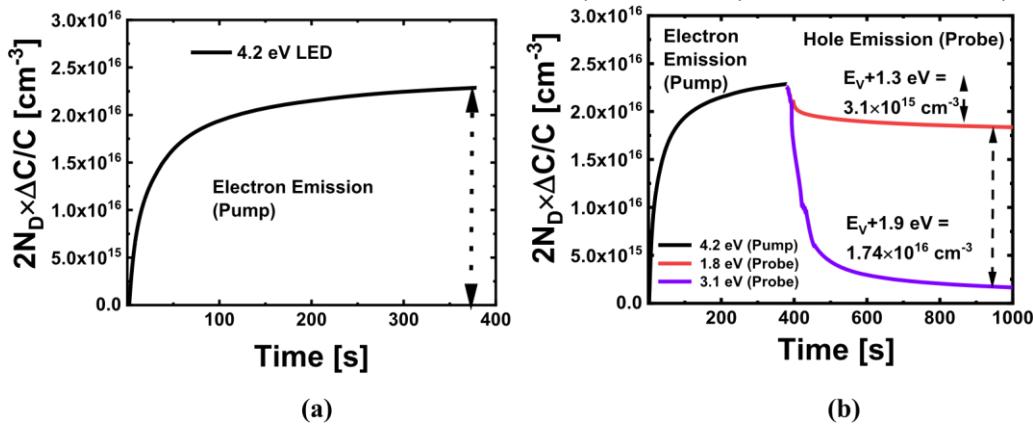
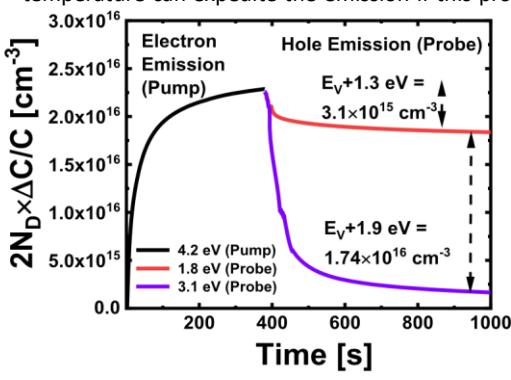


FIG. 4. (a) Majority carrier emission process accomplished using a pump light source representing the electron emission process (emptying the state). The trap concentration measured as a function of time closely matched the $2 \times 10^{16} \text{ cm}^{-3}$ implanted nitrogen concentrations measured from SIMS. (b) Minority carrier emission process (refilling with electrons resulting in hole emission) with two specific laser sources (probe) for precisely measuring the hole trap concentrations described in the double beam DLOS. The measured trap concentrations from electron and hole emission processes perfectly matched.

that is also the primary source of carrier compensation that we have earlier demonstrated.⁵

With the $E_v+1.9$ eV state appearing to be satisfactorily associated with the $E_c-2.9$ eV level attributed to N_{OIII} , and with the concentration of the state closely matching between both electron emission and hole emission DLOS measurements,⁵ further characterization of the $E_v+1.3$ eV state is necessary to gain a complete understanding of the DLOS behavior for N doped β -Ga₂O₃. To accomplish this, we have employed an optical isothermal defect spectroscopy method. This spectroscopy combines double-beam DLOS spectroscopy and conventional thermal DLTS measurements. Optical isothermal spectroscopy has certain limitations and can only be used to characterize defect states closer to either of the bands. Since $E_v+1.3$ eV is relatively close to the valence band and its thermal emission time constant can be extracted within the temperature range of our DLTS measurement, characterization of this defect level by optical isothermal DLTS is viable. Using the 4.2 eV pump light source to empty electrons from this state as an effective "hole filling pulse," subsequent isothermal DLTS can then be used to emit holes and monitor this effect on the resultant thermal capacitance transient, similar to a standard DLTS

experiment. The hole thermal emission process is immediately measured after turning off the 4.2 eV light source (i.e., hole-filling pulse). A schematic of optical isothermal measurement is shown in Fig. 5(a) to visualize the process. After the electron emission process to the conduction band, the occupancy of both $E_c-2.9$ eV/ $E_v+1.9$ eV and $E_v+1.3$ eV defect states change because the trapped electrons have been optically emitted to the conduction band, and this "empty electron" condition is maintained by virtue of the measurement occurring in the depletion region, where there are no free electrons for re-capture. However, the trapped hole or empty electron state would have thermal emission rates that are exponentially dependent on temperature, i.e., increasing the temperature can expedite the emission if this process is genuinely



(b)

occurring and can be measured by DLTS. Hence, the optical isothermal measurements were conducted between 415 and 450 K in steps of 5 K to expedite the thermal emission process. The raw transients measured from isothermal experiments are exponentially decaying, and a graph of individual time constants obtained from the boxcar integrator applied to the capacitance transients at each temperature is shown in Fig. 5(b). The method for extracting and analyzing the time constants is explained in Turchanikov *et al.*³² The temperature range was chosen due to the maximum temperature limits of our probe station (450 K) and a practical lower limit to ensure that the hole emission time constant could be measured within a reasonable time window. Again, emission from the $E_v+1.9$ eV state is not observable in this temperature range since it is too far from the valence band to be thermally ionized.

The analyzed spectra are plotted similarly to conventional DLTS spectra with a time constant (1/emission rate) and temperature as variables shown in Fig. 5(b). The measured peaks at specific temperatures were fitted to an Arrhenius plot shown in Fig. 5(c), and the obtained trap energy of $E_v+1.27$ eV closely matches what was observed using double-beam DLOS measurement, consistent with $D_{FC} = 0$ eV that predicts the optical and thermal emission energies would be nearly identical as noted earlier. From the optical

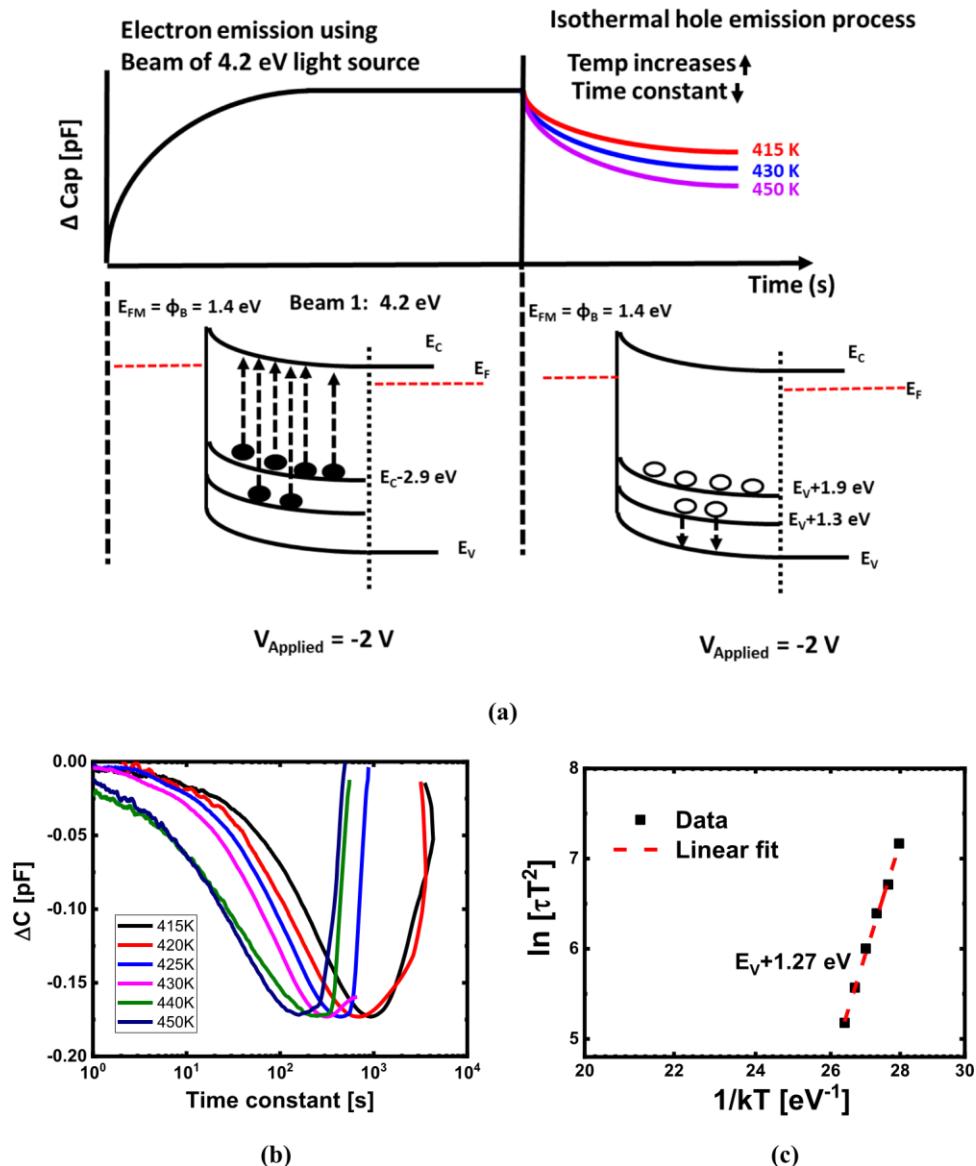


FIG. 5. (a) Optical isothermal emission schematic showing the thermally stimulated emission process used to detect the $E_V + 1.3 \text{ eV}$ state instead of a secondary light source (probe), along with illustrative band diagrams showing the optical and thermal emission processes. (b) Capacitance plotted similarly to DLTS spectra as a function of derived time constants from the boxcar integrator at various temperatures. (c) The resultant Arrhenius plot from the peak positions enables the extraction of the corresponding trap

isothermal DLTS measurements, the trap concentration of the $E_V + 1.3 \text{ eV}$ state was found to be $3.3 \times 10^{15} \text{ cm}^{-3}$, matching the double beam DLOS results, establishing self-consistency between these very different thermal and optical measurement methods. Interestingly, the x-intercept from the Arrhenius plot can be used to estimate the hole-effective mass, as follows:³³

$$\ln(T_{-2}) = (E_V + E_T) - \ln(\sigma_p \gamma_p). (1) \quad e_h \quad k_b T$$

Here, T is the temperature, e_h is the hole emission rate, k_b is the Boltzmann constant, σ_p is the hole thermal cross section, and γ_p is a constant defined by hole thermal velocity and hole density of states. Based on the slow hole emission properties, assuming a typical range of hole capture cross section values of $\sim 10^{-15} - 10^{-17} \text{ cm}^2$, the resultant calculated hole effective mass range from this analysis would be

energy, which matches the value obtained from the double-beam DLOS experiment.

be $(40\text{--}1000) \times m_0$. These values are consistent with the theoretical calculations.³⁴⁻³⁸ It is worth noting again that DLTS detection of a hole trap is possible because the experiment occurs within the depletion region electric field.

In addition, to demonstrate that hole emission from $E_V+1.3$ eV is only observed after N-doping and is related to N, we performed double-beam DLOS on the HVPE sample without nitrogen implantation, illustrated in Fig. 6. The DLOS spectra and the summary of the defect states have been reported previously.⁵ The double beam experiment was performed with the pump source photon energy maintained at 4.2 eV while the probe source energy was applied for photon energies of 1.9 and 3.0 eV. As shown in Fig. 6, no hole emission was observed, which is in contrast to the strong hole emission transients for the N-doped samples shown earlier in Fig. 4(b). This comparison of double-beam DLOS results for HVPE materials with and without N doping demonstrates that this hole emission process at $E_V+1.3$ eV is due to N doping.

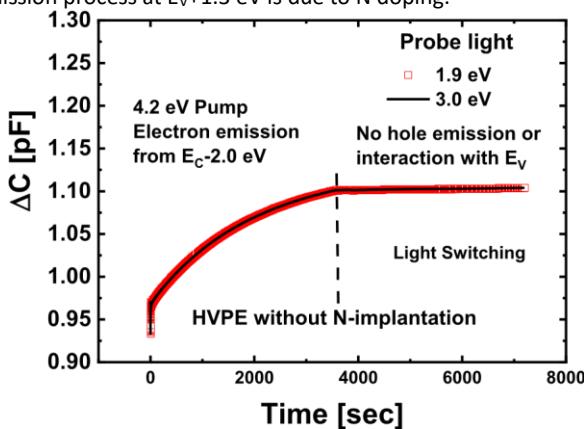


FIG. 6. Electron emission from $E_C-2.0$ eV was accomplished with a pump source of 4.2 eV, shown on the left side of the dashed vertical line. Switching from the pump to the 1.9 and 3.0 eV probe source on the right side of the dashed vertical line did not result in negative transients, indicating that no hole emission is observed without N doping for these samples.

In conclusion, this study comprehensively explains the dominant N deep acceptor level created in N-doped $\beta\text{-Ga}_2\text{O}_3$. It elucidates and reconciles the observed hole emission features in DLOS, attributing them to measurements conducted within the depletion region under electric fields. Both electron emission from $E_C-2.9$ eV and hole emission from $E_V+1.9$ eV appear to stem from the same energy level, identified as N_{III} in nitrogen-doped $\beta\text{-Ga}_2\text{O}_3$, the primary source of carrier compensation for N-doped $\beta\text{-Ga}_2\text{O}_3$. Optical cross section analysis reveals a high D_{FC} associated with both electron emission (1.4 eV) and hole emission (0.8 eV) from the same energy level, suggesting the presence of two distinct atomic configurations. Double beam experiments accurately pinpoint the defect location in the bandgap and enable quantitative

characterization of emission processes associated with both conduction and valence bands. Furthermore, these experiments revealed an unexpected state at $E_V+1.3$ eV that was thoroughly investigated through double-beam DLOS and optical isothermal measurements. A zero D_{FC} energy associated with the $E_V+1.3$ eV defect level suggests no lattice distortion or a nearly flat valence band transition. The nearly perfect match between the energy level calculated from double-beam DLOS and the optical isothermal spectroscopy further supports this conclusion. This specific state has been exclusively observed in N co-doped $\beta\text{-Ga}_2\text{O}_3$, strongly suggesting its association with nitrogen.

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AUTHOR DECLARATIONS Conflict of Interest

The authors have no conflicts to disclose.

Author Contributions

Hemant Ghadi: Conceptualization (lead); Data curation (lead); Formal analysis (lead); Investigation (lead); Methodology (lead); Validation (lead); Visualization (lead); Writing – original draft (lead); Writing – review & editing (lead). **Evan Cornuelle:** Conceptualization (equal); Data curation (equal); Formal analysis (equal); Investigation (equal); Writing – review & editing (equal). **Joe F. McGlone:** Conceptualization (equal); Formal analysis (equal); Investigation (equal); Writing – review & editing (equal). **Alexander Senkowski:** Investigation (equal); Resources (equal); Writing – review & editing (equal). **Shivam Sharma:** Investigation (equal); Resources (equal); Writing – review & editing (equal). **Man Hoi Wong:** Conceptualization (equal); Formal analysis (equal); Investigation (equal); Resources (equal); Visualization (equal); Writing – review & editing (equal). **Uttam Singisetti:** Conceptualization (equal); Investigation (equal); Resources (equal); Writing – review & editing (equal). **Steven A. Ringel:** Conceptualization (equal); Formal analysis (equal); Funding acquisition (equal); Methodology (equal); Resources (equal); Supervision (equal); Validation (equal); Visualization (equal); Writing – original draft (equal); Writing – review & editing (equal).

DATA AVAILABILITY

The data that support the findings of this study are available from the corresponding author upon reasonable request.

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